

COPY OF PAPERS  
ORIGINALLY FILED

RECEIPT

Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

JOAN WANG

Serial No.: 09/882,141

Filed: June 15, 2001

For: METHOD OF ETCHING HIGH ASPECT  
RATIO OPENINGS IN SILICON

RECEIVED

MAR 05 2002

IC 1700

REQUEST FOR CORRECTED FILING RECEIPT

To: Assistant Commissioner for Patents  
Washington, DC 20231

Sir:


The filing receipt for the above-identified application, a copy of which is attached, is incorrect in that there is only a single inventor, JOAN WANG, for parent application 08/867,229, rather than the three inventors listed on the filing receipt for this divisional application.

Please issue a corrected filing receipt.

Respectfully submitted,

JOAN WANG

By

  
Birgit E. Morris

Reg. No. 24,484



COPY OF PAPERS  
ORIGINALLY FILED

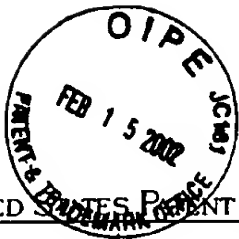
\_\_\_\_\_ Docket No. AM1562D1

Birgit E. Morris, Esq  
16 Indian Head Road  
Morristown, NJ 07960  
(973-656-9591

Please continue to send all correspondence to

Patent Counsel  
Applied Materials, Inc  
PO Box 450A  
Santa Clara, CA 95054

**RECEIVED**  
MAR 05 2002  
IC 1700



inv?

COPY OF PAPERS  
ORIGINALLY FILED

Page 1 of 3

54

Please correct invs

NO CER

UNITED STATES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS  
UNITED STATES PATENT AND TRADEMARK OFFICE  
WASHINGTON, D.C. 20231  
www.uspto.gov

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/882,141	06/15/2001	1733	710	AM1562D1	4	6	1

CONFIRMATION NO. 8856

FILING RECEIPT



\*OC000000006416924\*

Patent Counsel  
Applied Materials, Inc  
PO Box 450A  
Santa Clara, CA 95052

RE

001

Date Mailed: 08/13/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

**Applicant(s)**Yiqiong Wang, Morgan Hill, CA;  
~~Maocheng Li, Fremont, CA;~~  
~~Shaohai Pan, San Jose, CA;~~**Domestic Priority data as claimed by applicant**

THIS APPLICATION IS A DIV OF 08/867,279 06/02/1997

RECEIVED  
MAR 05 2002  
IC 1700**Foreign Applications**

If Required, Foreign Filing License Granted 08/10/2001

Projected Publication Date: 11/22/2001

Non-Publication Request: No

Early Publication Request: No

**Title**

Method of etching high aspect ratio openings in silicon

**Preliminary Class**

156

BEST AVAILABLE COPY



## UNITED STATES PATENT AND TRADEMARK OFFICE

FILE COPY

 COMMISSIONER FOR PATENTS  
 UNITED STATES PATENT AND TRADEMARK OFFICE  
 WASHINGTON, D.C. 20231  
 www.uspto.gov


Bib Data Sheet

CONFIRMATION NO. 8856

<b>SERIAL NUMBER</b> 09/882,141	<b>FILING DATE</b> 06/15/2001 <b>RULE</b>	<b>CLASS</b> 156	<b>GROUP ART UNIT</b> 1765	<b>ATTORNEY DOCKET NO.</b> AM1562D1	
<b>APPLICANTS</b> Yiqiong Wang, Morgan Hill, CA; <b>** CONTINUING DATA *****</b> THIS APPLICATION IS A DIV OF 08/867,229 06/02/1997 <b>** FOREIGN APPLICATIONS *****</b> <b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 08/10/2001</b>					
Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowance Verified and Acknowledged _____ Examiner's Signature Initials		<b>STATE OR COUNTRY</b> CA	<b>SHEETS DRAWING</b> 4	<b>TOTAL CLAIMS</b> 6	<b>INDEPENDENT CLAIMS</b> 1
<b>ADDRESS</b> Patent Counsel Applied Materials, Inc PO Box 450A Santa Clara ,CA 95052					
<b>TITLE</b> Method of etching high aspect ratio openings in silicon					
<b>FILING FEE RECEIVED</b> 710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		